	Application No.	Applicant(s)
Notice of Allowability	10/707,668	HUNG ET AL.
	Examiner	Art Unit
	Thao P. Le	2818
The MAILING DATE of this communication appears on the cover sheet with the correspondence address All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTOL-85) or other appropriate communication will be mailed in due course. THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS. This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308.		
1. This communication is responsive to <u>09/20/04</u> .		
2. The allowed claim(s) is/are <u>10-14 and 16-20</u> .		
3. The drawings filed on 31 December 2003 are accepted by the Examiner.		
<ul> <li>4. Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).</li> <li>a) All b) Some* c) None of the:</li> <li>1. Certified copies of the priority documents have been received.</li> <li>2. Certified copies of the priority documents have been received in Application No.</li> <li>3. Copies of the certified copies of the priority documents have been received in this national stage application from the International Bureau (PCT Rule 17.2(a)).</li> <li>* Certified copies not received:</li> </ul>		
Applicant has THREE MONTHS FROM THE "MAILING DATE" of this communication to file a reply complying with the requirements noted below. Failure to timely comply will result in ABANDONMENT of this application.  THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.		
5. A SUBSTITUTE OATH OR DECLARATION must be submitted. Note the attached EXAMINER'S AMENDMENT or NOTICE OF INFORMAL PATENT APPLICATION (PTO-152) which gives reason(s) why the oath or declaration is deficient.		
<ul> <li>6. CORRECTED DRAWINGS (as "replacement sheets") must be submitted.</li> <li>(a) including changes required by the Notice of Draftsperson's Patent Drawing Review (PTO-948) attached</li> <li>1) hereto or 2) to Paper No./Mail Date</li> <li>(b) including changes required by the attached Examiner's Amendment / Comment or in the Office action of Paper No./Mail Date</li> <li>Identifying indicia such as the application number (see 37 CFR 1.84(c)) should be written on the drawings in the front (not the back) of</li> </ul>		
each sheet. Replacement sheet(s) should be labeled as such in the header according to 37 CFR 1.121(d).		
7. DEPOSIT OF and/or INFORMATION about the deposit of BIOLOGICAL MATERIAL must be submitted. Note the attached Examiner's comment regarding REQUIREMENT FOR THE DEPOSIT OF BIOLOGICAL MATERIAL.		
Attachment(s) 1. ☑ Notice of References Cited (PTO-892) 2. ☐ Notice of Draftperson's Patent Drawing Review (PTO-948)	6. ☐ Interview Sumr	
3. Information Disclosure Statements (PTO-1449 or PTO/SB/0	Paper No./Mai 8), 7. 🔀 Examiner's Am	
	9. Other  David Nelms	tement of Reasons for Allowance
Supervisory Patent Examiner Technology Center 2800		

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## **DETAILED ACTION**

# **Response to Amendment**

This Office Action is in response to Amendment filed on 09/20/04.

Claims 1-9, 15 have been cancelled.

Claims 10, 12-14 have been amended.

Claims 10-14, 16-20 are pending.

### **EXAMINER'S AMENDMENT**

Amend claim 10 as following:

Delete the word "a" before:

"...masks;

removing the first patterned photoresist layer;"

#### Reason for allowance

Claims 10-14, 16-20 are allowed. The following is an examiner's statement of reason for allowance: None of the references of record teaches or suggests the claimed limitations having a method of forming a flash memory device including, among other steps, etching the substrate until penetrating through a junction between the first source/drain region and the first conductive type second well region to form a first trench by using the first patterned photoresist layer and the stacked gate structures with the spacer as masks; etching the portion of the substate to the second conductive type first well region to form a pair of second trenches by using the second patterned photoresist layer; ion implanting into the sidewall and bottom of the second trenches to prevent a short circuit between the p-well

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region and contact, forming a source line having lower resistance to connect the source region of every memory cell.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance".

### **Conclusion**

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Thao P. Le whose telephone number is 571-272-1785. The examiner can normally be reached on M-T (7-6).

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, David Nelms can be reached on 571-272-1787. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

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Thao P. Le Examiner Art Unit 2818

November 1, 2004

**David Nelms** Supervisory Patent Examiner Technology Center 2800